



INSTITUTE OF NANO OPTOELECTRONICS RESEARCH AND TECHNOLOGY (INOR)

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FABRICATION PROCESS REQUEST FORM

Requestor Name	:	
Contact No.	: Ema	nail : Date :
School/Company	:	
Category	: INOR Staff/Student	Other Dept. :
Sample Type	: Powder Thin Film	No. of Sample :
Materials	<u> </u>	
Substrate	:	
Please Tick Appropriate Box		
EQUIPMENT EQUIPMENT		
3-Zone Furnace Metallization Oxidation 3-Zone Furnace Degas Vacuum UV-Ozone Clean Glove Box Vacuum Spin Coater Hotplate Laminar Flow Fume Hood	-	E-Beam Evaporator Without source material and crucible With source material & crucible Inductive Couple Plasma Etching System (ICP) Using Cl & BCl3 (e.g. GaN) Other gases except Cl & BCl₃ (e.g. Si, ITO, ZnO) Rapid Thermal Processor System (RTP) Mask less Lithography [direct write, complete process] Sample with pre-coat PR Sample without pre-coat PR
Other information about the sample (e.g. sample stability/temperature):		
Requestor Signature: Supervisor Approval: (if Students, need to get the approval from Supervisor)		

- Remarks:
 * Please refer to the analysis/equipment usage charges on INOR website.
 ** Any incomplete form will not be processed.
 *** Quotation will be sent through requestor's email within 3 working days.